







Water-cooled EST dry vacuum pump for powdry, corrosive applications



The EST is qualified for harsh applications generating reactive chemical by-proudcts. It manages high gas loads and enhanced powdry by-product handling. The compact design allows high operating temperature and corrosion resistant material.

BENEFITS

- High operating temperature
- High gas loading stability
- Flexible gas throughput





Models		EST10	EST25	EST100	EST200	EST300	EST500
Max pumping speed in I/min		1,000	2,500	100,000	20,000	30,000	50,000
Max pumping speed in m³/h		60	150	600	1,200	1,800	3,000
Ultimate pressure Pa Gas ballast: on		2.7	2.7	0.4	0.4	0.4	0.4
Power at ultimate Pressure in kW		2.3	3.0	3.2	3.2	4.5	4.6
Cooling requirements		water cooling					
Noise emission dB(A)		60	60	60	60	60	60
Size in mm	W	1,100	1,140	1,140	1,140	1,140	1,140
	L	410	410	410	410	520	520
	н	532	531	946	946	948	948
Weight in kg		260	300	380	430	500	550
Application form		harsh duty applications					

APPLICATIONS FOR EST

HDP-CVD RTP SACVD MOCVD PECVD LPCVD ALD

APPLICATIONS RANGE



EBARA is a worldwide leading global manufacturer of vacuum and semiconductor systems used in the production of wafers, liquid crystals, solar cells and other products requiring advanced technology.

EBARA supports



EBARA Precision Machinery Europe (EPME) is part of the Japanese EBARA Group and employs approximately 150 people in Europe. The portfolio includes dry and turbo molecular vacuum pumps as well as gas abatement systems. In addition, EPME sells state-of-the-art CMP tools, wafer bevel polishing and substrate coating systems. In Europe, EPME has a central warehouse and an overhaul centre for vacuum pumps.

